

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In Re Application of:

Francisco Arias et al.

Examiner: Mathieu D Vargot

Serial No.: 10/727,124

Group Art Unit: 1791

Filing Date: December 3, 2003

Confirmation No: 4751

Title: METHOD OF MANUFACTURING MICRONEEDLE STRUCTURES USING SOFT LITHOGRAPHY AND PHOTOLITHOGRAPHY

OK TO ENTER: /M.V./

**AMENDMENT UNDER 37 CFR 1.116**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is in response to the Final Office Action mailed from the PTO on December 17, 2009.

**Listing of the Claims** begins on page 2 of this paper.

**Remarks** are found on page 4 of this paper.